



Docket No.: 6601P036C

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

EMIR GURER, ET AL.

Application No.: 09/874,073

Filed: June 4, 2001

For: **PLASMA DEPOSITION OF SPIN CHUCKS TO
REDUCE CONTAMINATION OF SILICON
WAFERS**

Art Group: 1763

Examiner: Ram N. Kackar

PETITION FOR EXTENSION OF TIME PURSUANT TO 37 C.F.R. § 1.136(a)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F. R. § 1.136(a), Applicants for the above-identified application respectfully Petition the Commissioner for a two (2) month extension of time, extending the period for response to November 16, 2003, from the Final Office Action dated June 16, 2003. The petition filing fee of \$420.00 and a Response to Final Office Action are attached.

If it should be determined that a longer extension of time is required to prevent this application from being abandoned, please charge any additional fees to Deposit Account No. 02-2666. A copy of the Fee Transmittal is enclosed for deposit account charging purposes.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

Date:

10/29/03

Tom Van Zandt, Reg. No. 43,219

CERTIFICATE OF MAILING/TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Christine Donahue

10-29-03

Date

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